

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:	)	
	)	Examiner:
Yuichiro Nakamura et al.	)	
	)	Group Art Unit:
Application No.:	)	
	)	
Corresponding International Filing No.:	)	
<b>PCT/JP2005/002209</b>	)	
	)	
Filed: Herewith	)	
	)	
For: SPUTTERING TARGET WITH	)	
FEW SURFACE DEFECTS, AND	)	
SURFACE PROCESSING	)	
METHOD THEREOF	)	

Mail Stop PCT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**SECOND PRELIMINARY AMENDMENT**

Sir:

Please amend the above-identified patent application as follows.

**Amendments to the Specification** begin on page two of this paper.

**Amendments to the Claims** are reflected in the listing of claims which begins on page three of this paper.

**Remarks** begin on page five of this paper.